



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: JAFARIAN-TEHRANI et al.  
Application No.: 10/816,211  
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Examiner: UNKNOWN  
Group No.: 1763  
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Title: METHODS AND ARRAY FOR CREATING A  
MATHEMATICAL MODEL OF A PLASMA  
PROCESSING SYSTEM

INFORMATION DISCLOSURE STATEMENT

**US PATENT DOCUMENTS**

Examiner Initials	Cite No.	Document Number	Publication Date	Name of Patentee or Applicant	Reference to Related Case

**OTHER DOCUMENTS**

Examiner Initials	Cite No.	Description	T
Xur	1	STOUT et al., "Modeling Plasma Tools: Reactor and Feature Scales," pp. 1-6, <a href="http://www.google.com/search?q=cache:IPSvCEvzITsJ:cfdpplasma.trancetechno.com/vmic_2000.pdf+%22inductively+coupled+plasma%22+%22shower+head%22&amp;hl=en&amp;ie=UTF-8">http://www.google.com/search?q=cache:IPSvCEvzITsJ:cfdpplasma.trancetechno.com/vmic_2000.pdf+%22inductively+coupled+plasma%22+%22shower+head%22&amp;hl=en&amp;ie=UTF-8</a>	

Examiner Signature	<i>MPaslin</i>	Date Considered	5-12-08
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